Silicon Detectors - Outline

Part I

- Physics Requirements
- Solid State Detector Physics
 - Field maximum at junction side
 - Carrier mobilities define current signal
- Detector Design
 - Radiation hard structures
 - Care in internal fields, oxide layers to avoid breakdown
- Radiation Damage
 - Increase in Vdep/Type inversion
 - Increase in I_{leakage}

• Part II

- Electronics and readout
- Mechanical and construction
- Production and Testing

References

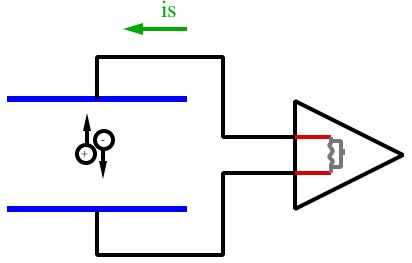
- Radeka, Ann. Rev. Nucl. Part. Sci. 1988, 217-277.
- Helmudt Spieler lecture notes (www-physics.lbl.gov/~spieler)
- Sze, Physics of Semiconductor Devices
- CMS and ATLAS notes

R. Lipton

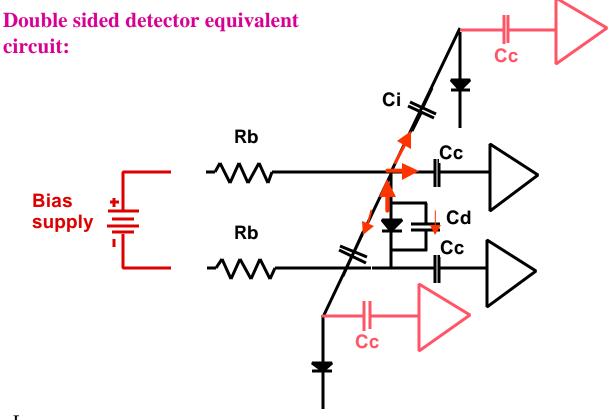
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Electronics and Readout - Equivalent Circuit

Simple picture of "ion chamber" current



Moving charge in the gap induces a current in the circuit



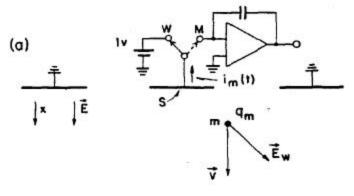
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Electronics and readout - signal development

Signal induced by moving charges depend on *work* done by circuit. The charge induced on an electrode depends on the coupling between the moving charge and the electrode.

RADEKA

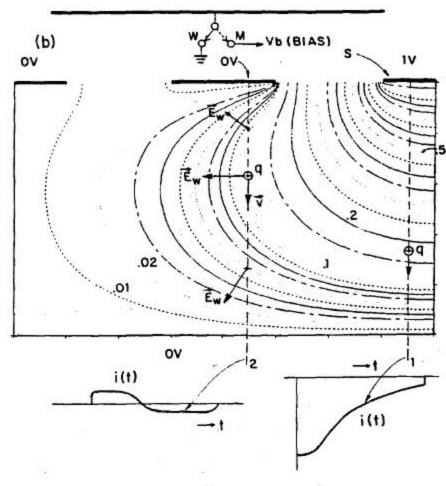
In a multi-electrode system the induced current on an electrode depends on the velocity of the charge and the value of the effective "weighting" field



Weighting field determined by
putting 1V on strip,
grounding all other
electrodes

$$i = q\vec{E}_{\scriptscriptstyle W} \bullet m\vec{E}$$

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Electronics and readout - Capacitance

Capacitances:

 C_{ac} = coupling capacitance

~10pf/cm dependent on thickness and composition of dielectric.

Thin oxide - larger coupling capacitance, large signal, lower Vb, more fragile structure

 C_b = backplane capacitance

 $\sim\!0.1$ pf/cm - due to parallel plate front-back coupling, dependent on depletion

 C_i = interstrip capacitance

~ 1 pf/cm - usually dominant preamplifier load. Dependent on detector layout, surface and oxide charges, irradiation. Is larger for n-side due to p-stop coupling. Also larger for double metal devices

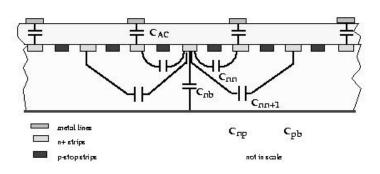
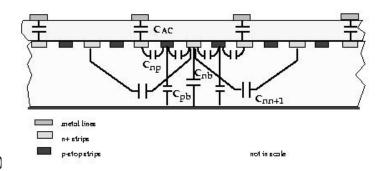


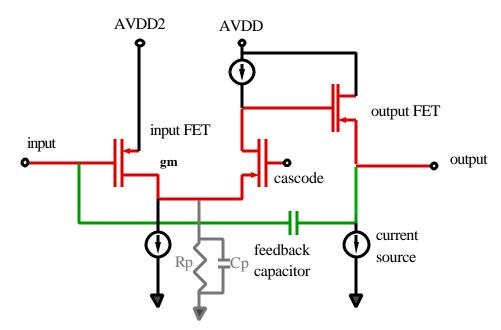
Figure 8,a



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Electronics and readout - The CMOS preamp

- Breakthrough (microplex chip) low noise compact preamplifiers can be fabricated using standard CMOS processes
 - Small amplifier pitches (40 microns)
 - Low noise
 - Radiation hard processes available



Basic equations:

$$\boldsymbol{t} = R_p C_p$$

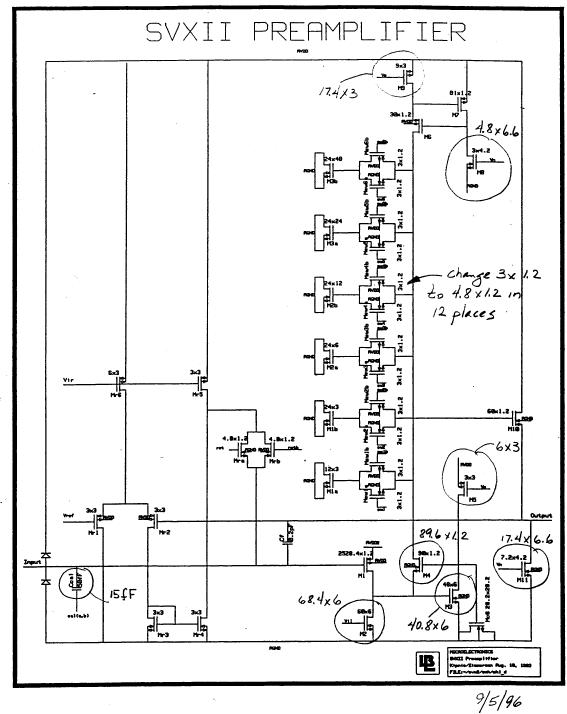
$$g_m = \frac{II_d}{IV_g}$$
 transductance

$$A_o = g_m R_p$$
 open loop gain

$$gain = 1/C_f$$
 volts/coulomb

$$\boldsymbol{t}_{in} = \boldsymbol{t}/A_o \, C_f$$

SVX II Front End



Signal/Noise

Noise sources:

• Preamp noise - due to charge fluctuations in input transistor. Proportional to load capacitance:

$$ENC = a + bC_{load}$$

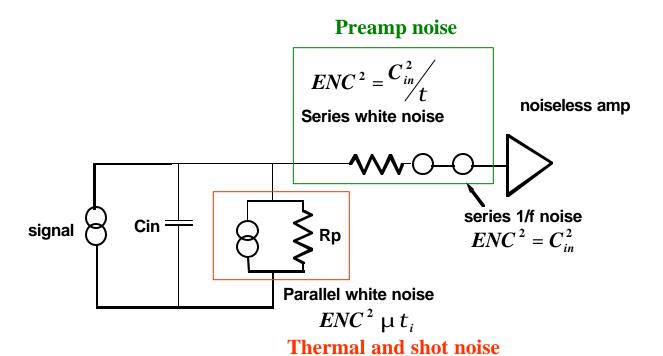
• Shot noise in trip leakage current

$$ENC = q_e \sqrt{N_e}$$

•Thermal noise in bias resistor

$$ENC = \sqrt{kTt/2R_b}$$

•Thermal noise of series resistors



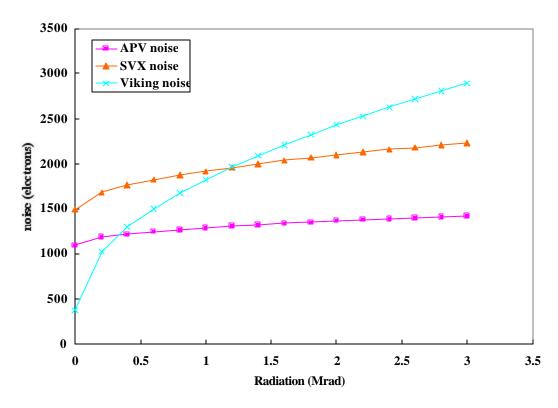
Signal/Noise

• Amplifiers can be optimized for noise performance in specific applications:

Silicon Readout chips

Chip	t	noise	Power	Application
Viking	1.5 ms	135e +12 e/pf	1.5 mW/ch	long strips, slow response,e+e-
SVX II/III	132 ns	490e+50 e/pf	5 mW/ch	Fermilab collider
\mathbf{APV}	25 ns	500e+30 e/pf		LHC (CMS)

Silicon Readout Chips



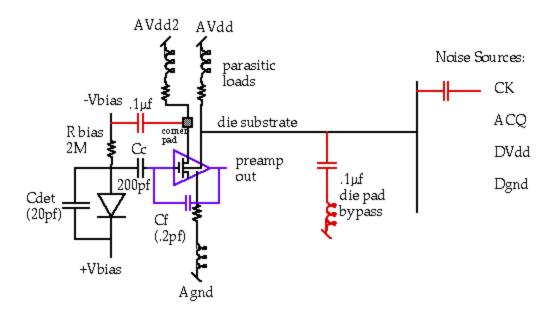
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Electronics and Readout

Real problems in a detector are often dominated by system design

- Power distribution and cabling
- Noise coupling from
 - other detectors
 - outside world (SCRs ...)
 - digital to analog sections of the chip
- Ground loops and uncontrolled current paths
- 98% of the work is on "Real World" problems

SVX 2 Front end equivalent circuit showing noise sources and suggested bypass



Pixel Detectors

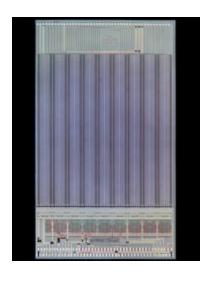
Two dimensional array of readout electrodes on a silicon detector

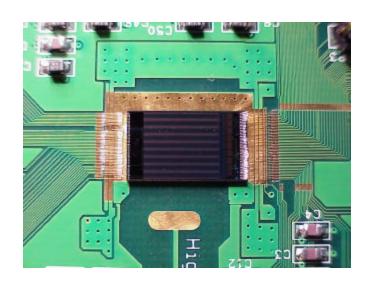
- Two dimensional readout
 - Typically rectangular (50x400 mm)
- Very low input capacitance S/N~150/1
- "Radiation hard" due to large S/N margin

Sounds great but...

- Connection to readout requires more complex "bump bonding" - "sandwich" of detector and readout using Indium or solder bumps
- Readout must be organized to efficiently identify and readout hit pixels. Challenging design.
- Amplifiers are distributed ... more complex cooling/services

BTEV FPIX1



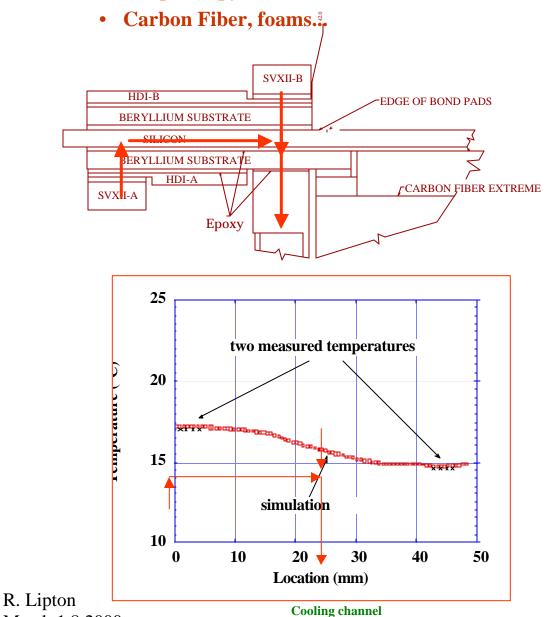


Mechanical and construction - Cooling

- Need to keep detectors at low temperature to control reverse annealing and leakage currents
 - Remove head from readout chips
 - High thermal conductivity, low mass materials
 - Be, BeO

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• Graphite (pyrolitic)



Thermal Runaway

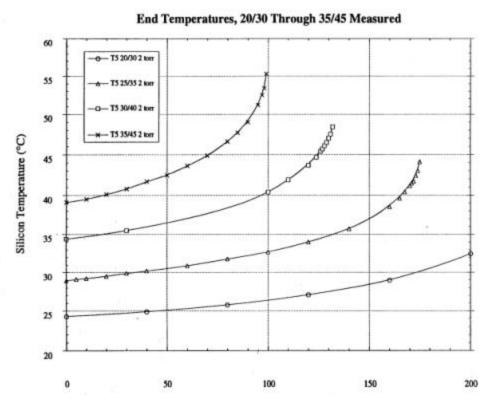
Irradiated detectors leakage currents increase as:

$$DI_{leak} = afV$$

Depletion voltages also increase with the result that the power generated by the detector itself Vbias x Ileak becomes significant. This power can cause a temperature rise which, in turn will increase the current:

$$I_{leak} = T^2 e^{-\frac{1.2eV}{2kT}}$$

causing "thermal runaway" and an unusable detector if the heat cannot be removed.

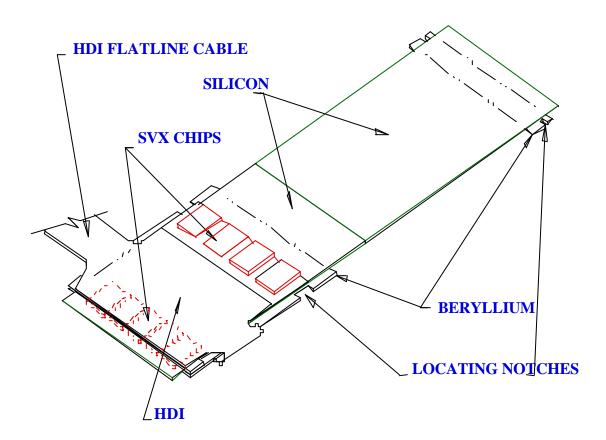


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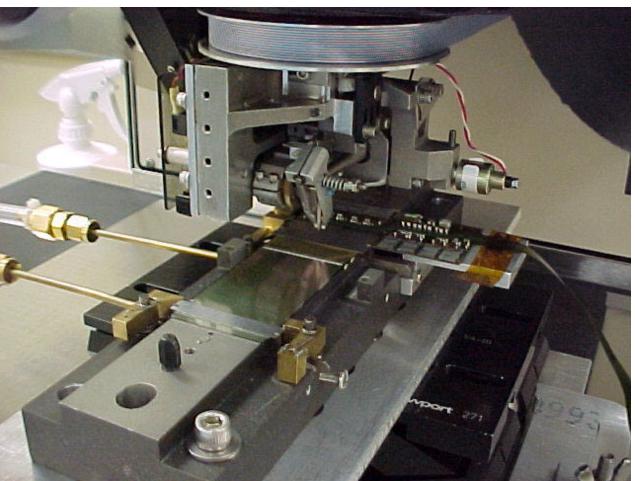
KEK/CDF study

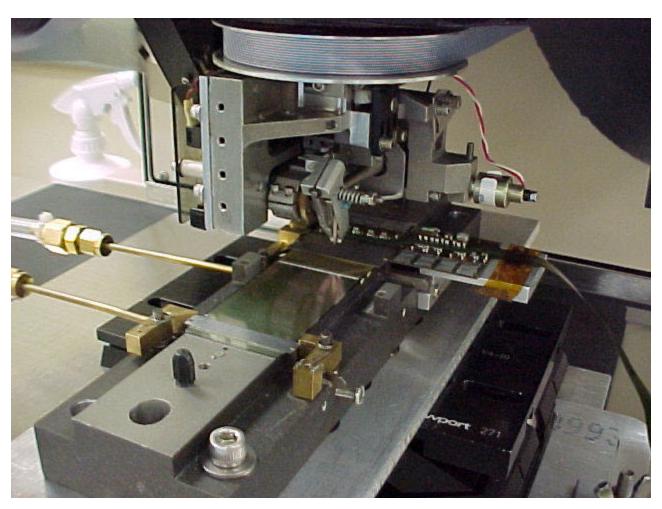
Mechanical and construction - Support

- Mechanical Support
 - alignment of assembly wrt support structure
 - 2-20 mm depending on trigger requirements
 - maintainance of alignment + fiducials
 - support of silicon crystals
 - detectors can bow ~100 mm
 - cooling of readout electronics
 - water/water-glycol/silicon oil/cleaning fluid
 - access for wirebonding/interconnects



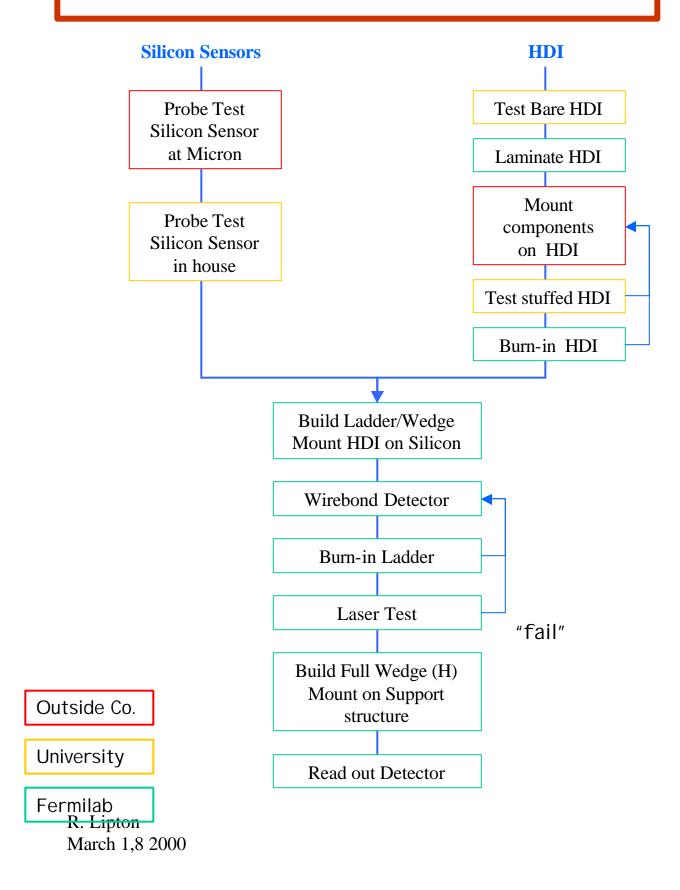






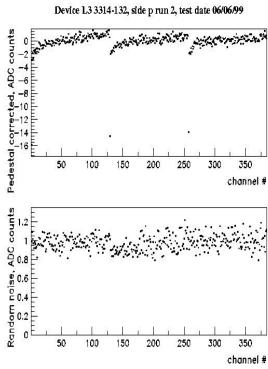


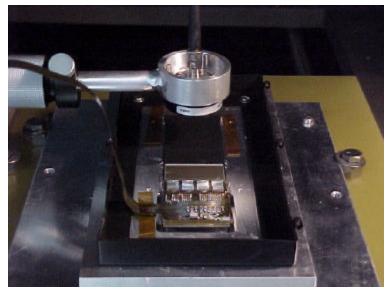
Production and Testing

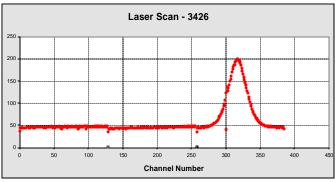


Production Testing









(Demarteau)

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Conclusions

- Silicon detectors are complex devices with substantial requirements for understanding the underying physics
 - Fields
 - Charge transport
 - Radiation damage
 - Thermal properties
 - Microelectronics

It's very easy to get burned

